

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoru Okamoto Art Unit : 1792  
Serial No. : 10/689,617 Examiner : Mahmoud Dahimene  
Filed : October 22, 2003 Conf. No. : 4799  
Title : METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD  
FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE

**MAIL STOP RCE**  
Commissioner for Patents  
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## INFORMATION DISCLOSURE STATEMENT

Applicant requests consideration of the references listed on the attached PTO-1449 form. Under 37 C.F.R. § 1.98 (a)(2)(ii), only copies of foreign patent documents and/or non-patent literature are enclosed. Copies of any listed U.S. patents or U.S. patent application publications can be provided upon request.

This filing is being made with the filing of a Request for Continued Examination and therefore it is believed that no fee is required. Nevertheless, please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date:March 10, 2008

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